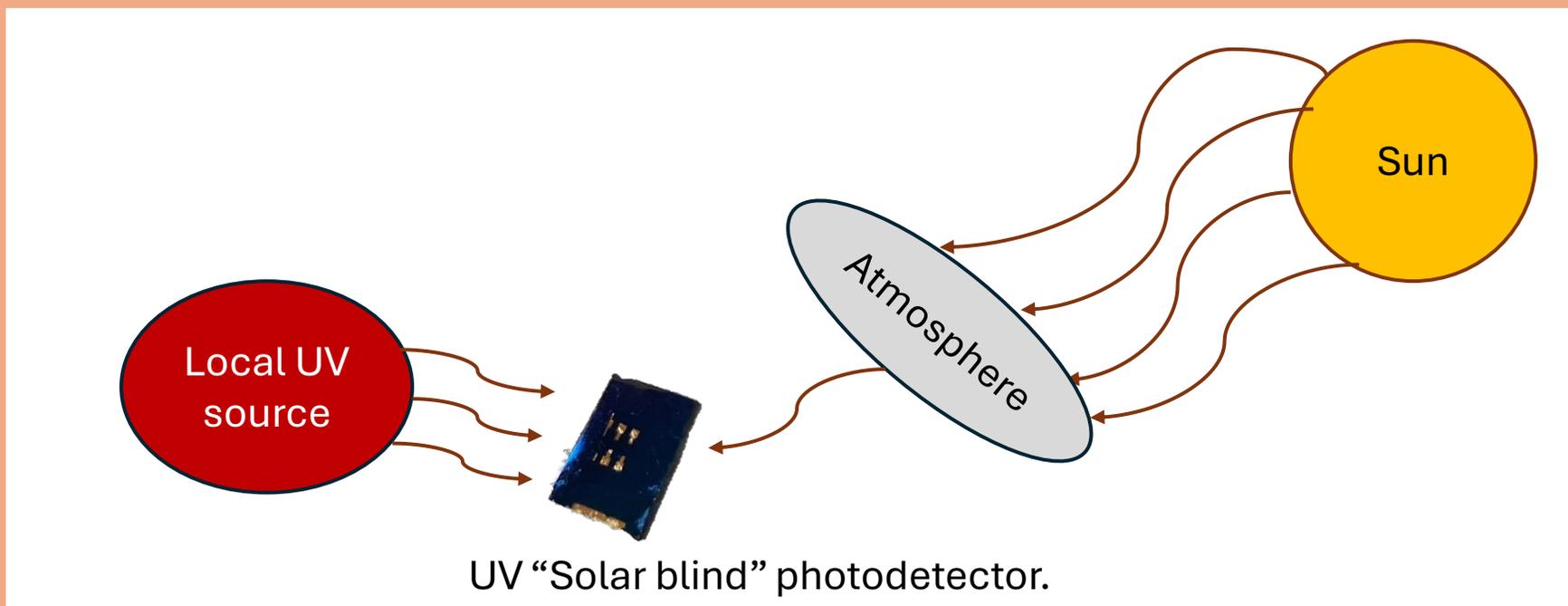


# Controlled Modification of $\text{Ga}_2\text{O}_3$ Interfaces for Photovoltaic and Photoconductive UV Detectors



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# M-S-M Fabrication

**Protective layer:** Gold (Au)

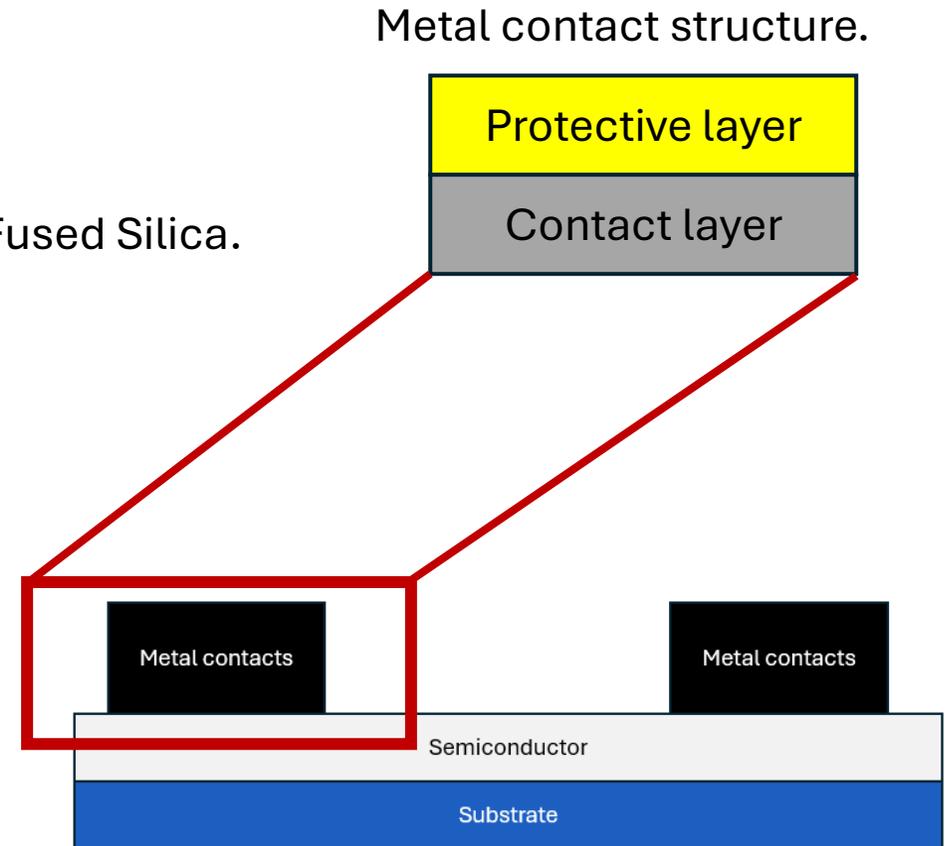
➤ Protects oxidation.

**Contact layer:** Nickel (Ni), Platinum (Pt), Titanium (Ti).

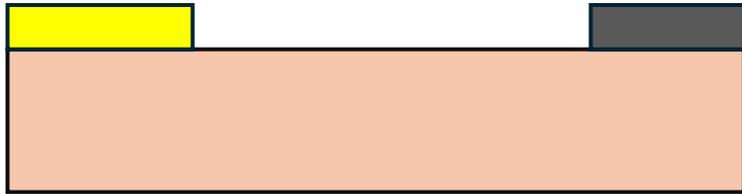
➤ Establishes the contact behavior.

**Substrates:** Si,  $SiO_2$  (monocrystalline),  $SiO_2$  (amorphous)-Fused Silica.

Material	Work function (eV)	$\Phi_B$ (eV)	Type of contact
$\beta - Ga_2O_3$	4.00 $\pm$ 0.05	-----	-----
Ni	4.95-5.52	0.95-1.52	Schottky
Pt	5.01-5.53	1.01-1.53	Schottky
Ti	4.3	0.3	Ohmic

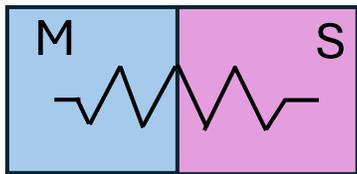


# Intended Photodectors

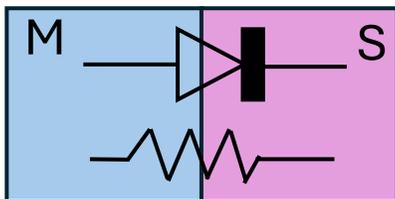


## Schottky photodiode

➤ Photovoltaic and Photoconductive mode.



-Ohmic contact behavior.

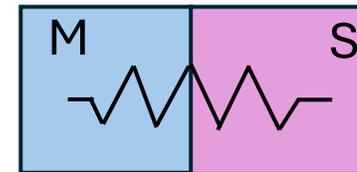


-Schottky contact behavior.



## Photoconductor

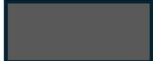
➤ Photoconductive mode.



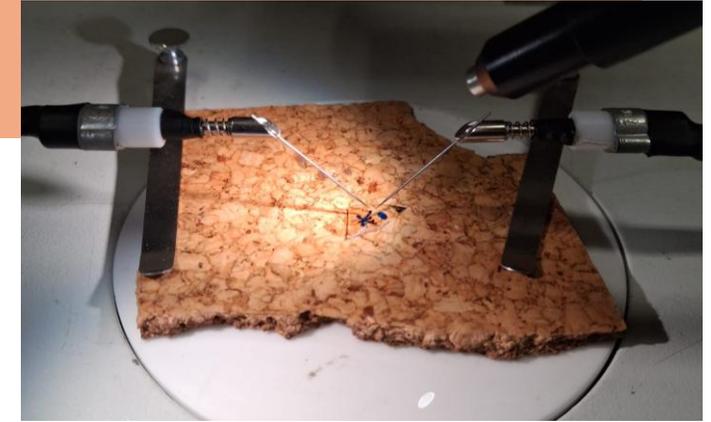
-Ohmic contact behavior.

 N-type semiconductor ( $\text{Ga}_2\text{O}_3$ ).

 Schottky contact.

 Ohmic contact.

# Characterization process



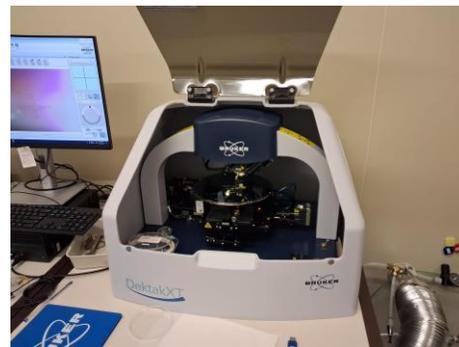
Electrical characterization (I-V) worktable.

## • Characterization techniques:

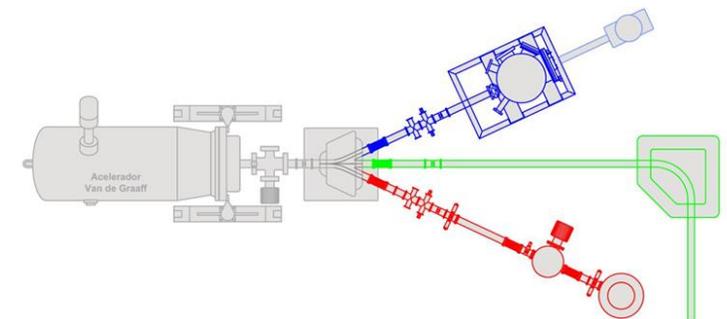
- Film Thickness- **Profilometry**;
- Crystalline phase and lattice parameters - **X-ray diffraction, PIXE**;
- Composition and thickness-**Rutherford backscattering spectrometry (RBS)**;
- Crystallinity of solids and Stress detection- **Raman spectroscopy**;
- Electrical characterization;
- Surface examination- **Atomic force microscopy(AFM)**;
- Surface morphology- **Scanning electron microscopy (SEM)**.



RAITH 150.



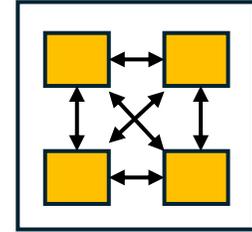
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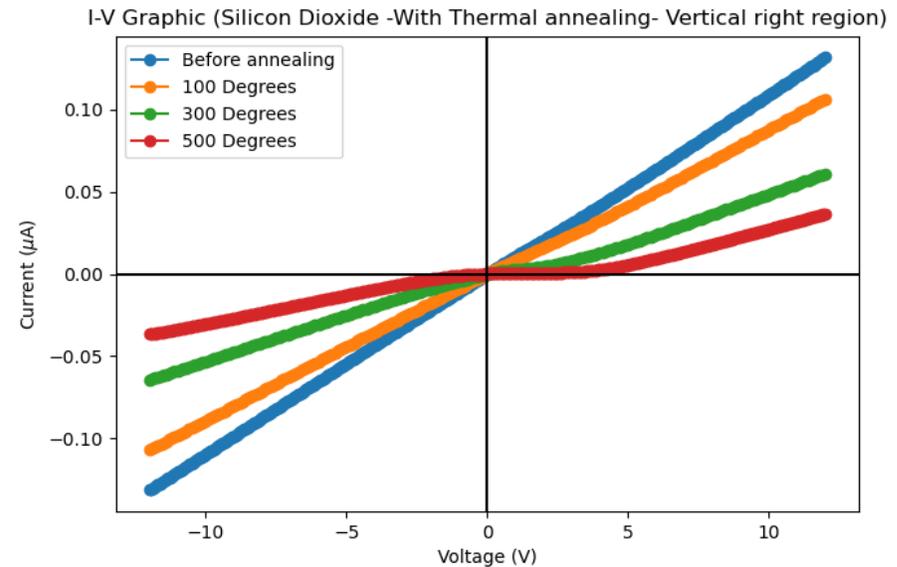
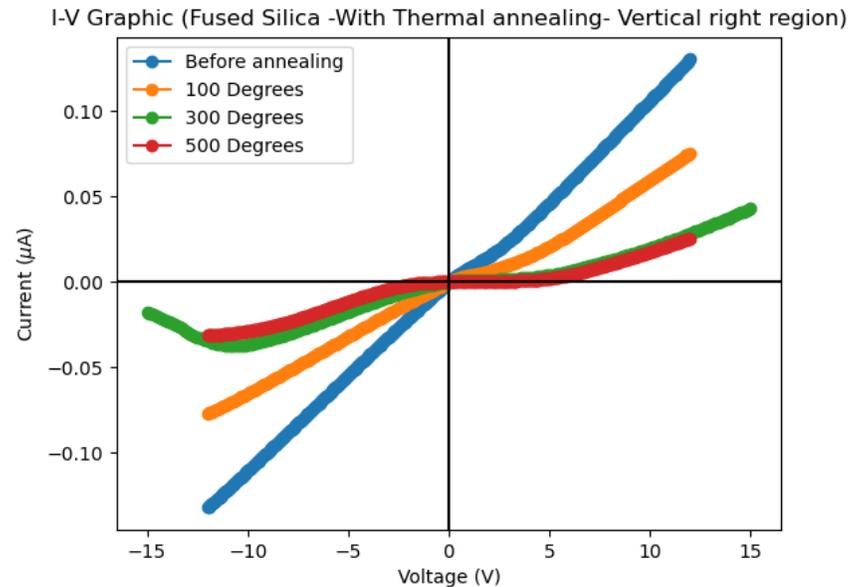
Accelerator Van de Graaff.

# Some Preliminary Results

- **Electrical characterization:**
  - Varying the annealing temperature.
    - Sample used: Au-Ni.



Metal contacts measured directions.



Conclusion: Increase of temperature



Change of contact behavior (Schottky).